

ABSTRACT

A method and system for determining a lifetime of a target for a physical vapor deposition tool (302), has, a mapping table (304a) of criteria for a minimum accumulating rate of Δ wafers fabricated by Δ target life for a target in the tool; and a database (304) recording Δ 5 wafers fabricated by Δ target life for a target in the tool; and a computer (306) retrieving the criteria from the mapping table and entering the criteria in the database; and the tool (302) reporting Δ wafers fabricated by Δ target life for a target in the tool (302) for comparison with the criteria.